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INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				ATTY DOCKET NO. BOW5075.01	SERIAL NO. 10/051,623	
MAY 21 2002 RECEIVED U.S. PATENT & TRADEMARK OFFICE JAN 17 2002				BOWER, ROBERT W.		
				FILING JANUARY 17, 2002	GROUP 2813 2829	
U.S. PATENT DOCUMENTS						
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS
FILING DATE IF APPROPRIATE						
FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS
TRANSLATION YES NO						
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
EP		Bower, Robert W.; LeBoeuf, L.; and Li, Y.A.; "TRANSPOSED SPLITTING OF SILICON IMPLANTED HYDROGEN AND BORON WITH OFFSET DISTRIBUTIONS," ECE Department, University of California, Davis, CA 95616, pp. 1-3, Il Nuovo Cimento, Vol. 19D, No. 12, pp. 1871-1873, 1 January 1998.				
EP		Bower, Robert W.; Li, Y.; and Chin, Yong J.; "THE HYDROGEN ION CUT TECHNOLOGY COMBINED WITH LOW TEMPERATURE DIRECT BONDING," ECE Department, University of California, Davis, CA 95616, pp. 1-3, Proceedings of SPIE, Vol. 3184, pp. 2-4, June, 1997.				
EXAMINER <i>Evan Pert</i>			DATE CONSIDERED <i>12-6-02</i>			

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INFORMATION DISCLOSURE CITATION
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MAY 21 2002 C34

Docket Number (Optional) BOW5075.1	Application Number 10/051,623
Applicant(s) BOWER, ROBERT W.	
Filing Date JANUARY 17, 2002	Group Art Unit 2813 2829

*EXAMINER INITIAL

RENTAL MARK OF C34

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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<i>EP</i>	Bruel, M.; "SILICON ON INSULATOR MATERIAL TECHNOLOGY," <i>Electronics Letters</i> , Vol. 31, No. 14, 6th July 1995.
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<i>EP</i>	Freund, L.B.; "A LOWER BOUND ON IMPLANT DENSITY TO INDUCE WAFER SPLITTING IN FORMING COMPLIANT SUBSTRATE STRUCTURES," <i>Applied Physics Letters</i> , Vol. 70, No. 26, 30 June 1997.
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